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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF: :
Sumi TANAKA, et al. : EXAMINER: MOORE, K.
SERIAL NO.: 09/646,343 :
FILED: September 18, 2000 : GROUP ART UNIT: 1763
FOR: FILM DEPOSITION :
APPARATUS :

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AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Official Action dated April 4, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Claims 1 and 8 are amended as follows:

1. (Once Amended) A film deposition apparatus comprising:
- a container forming a processing chamber for processing a target object;
 - a mounting table which is provided in the processing chamber and on which the target object is mounted;
 - a first heating apparatus provided in the mounting table, for heating the target object mounted on the mounting table;

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